

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant(s):	Renken et al.		
Title:	Process Condition Sensing Wafer and Data Analysis System		
Application No.:	10/685,550	Filing Date:	October 14, 2003
Examiner:	Samir M. Shah	Group Art Unit:	2856
Docket No.:	SENS.005US1	Conf. No.:	4924

Mail Stop RCE
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

REQUEST FOR CONTINUED EXAMINATION (RCE)

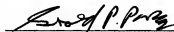
Dear Sir:

This is a Request for Continued Examination (RCE) under 37 C.F.R. § 1.114 of the above-identified application. Please consider the Response to Office Action and amendment, which is being filed herewith.

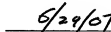
The RCE fee of \$790.00 required under 37 C.F.R. § 1.17(e) has been authorized via EFS to Deposit Account 04-0258. The Commissioner is hereby authorized to charge any additional fees, which may be required, or credit any overpayment to Deposit Account 04-0258. Please contact the undersigned with any questions concerning this request or the above-identified patent application.

FILED VIA EFS

Respectfully submitted,



Gerald P. Parsons
Reg. No. 24,486



Date

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